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3-17-01  
J. Antos

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of :  
Moshe FINAROV :  
Serial No. Not yet assigned : Group Art Unit: Not yet assigned  
Filed: July 26, 2000 : Examiner:  
:

For: AN APPARATUS FOR INTEGRATED MONITORING OF WAFERS AND FOR  
PROCESS CONTROL IN THE SEMICONDUCTOR MANUFACTURING AND A  
METHOD FOR USE THEREOF

**PRELIMINARY AMENDMENT**

Assistant Commissioner For Patents  
Washington, D. C. 20231

Sir:

Preliminary to examination of the above-referenced application, please amend the  
application:

**IN THE SPECIFICATION:**

On page 1, after the title, please insert the following:

--The present application is a continuation-in-part of U.S. Application Serial No.  
09/509,080 filed March 22, 2000, entitled AN APPARATUS FOR INTEGRATED  
MONITORING OF WAFERS AND FOR PROCESS CONTROL IN THE SEMICONDUCTOR  
MANUFACTURING AND A METHOD FOR USE THEREOF--.

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